Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L4	373	(chamber with (substrate or wafer)) and ((liner or shield) same ((heat or radiation) with (reflect or (low near\$3 emission))))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/27 16:58
L5	1	4 and (radiation adj emission adj coefficient)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR .	ON	2007/03/27 12:55
L6	10	4 and (radiation adj emission)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/27 12:56
L7	0	4 and ((low or non) adj (reflect or emissive))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/27 13:13
L8	7406	Teflon with (insulat\$3)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/27 14:13
L9	130	8 and (teflon with screw)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/27 14:14
L10	10	9 and (chamber with (substrate or wafer))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON .	2007/03/27 15:14
L11		radiation adj emission adj coefficient	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/27 15:14

L12	5	(chamber with (substrate or wafer))	US-PGPUB;	OR	ON	2007/03/27 17:01
		and ((liner or shield) same (polish\$2 near aluminum))	USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB			
L13	79	((liner or shield) same (polish\$2 near aluminum))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/27 17:01
L14	71	((liner or shield) same (polish\$2 adj aluminum))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/27 18:22
L15	6	"5885356".pn. or "5328556".pn. or "6096161".pn.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/27 18:23
S1	. 12	"5788799".pn. or "5798016".pn. or "5283414".pn. "6055927".pn. "4430547".pn.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/08 12:10
S2	10447	156/345.35,345.37.ccls. 134/1/1, 104.1.ccls. 216/67.ccls. 438/730. ccls. 219/121.43,121.54,121.51, 411.ccls. 315/111.81.ccls. 118/723mp,724,725.ccls.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/08 13:44
S3	41	(chamber vessel tank container reactor) and (support susceptor table) and (substrate wafer object) and ((heater heating) near (liner jacket)) and (fluorine same (aluminum titanium)) (bias adj means) and (etching near source) and (passivation near source) and (heater near (fasten\$ attach\$)) and (temperature near (regulator control))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/08 12:40

54	1	S2 and S3	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/08 12:38
S5		(chamber vessel tank container reactor) and (support susceptor table) and (substrate wafer object) and ((heater heating) near (liner jacket)) and (fluorine same (aluminum titanium)) (bias adj means) and (etching near source) and (passivation near source) and (heater near (fasten\$ attach\$)) and (temperature near (regulator control)) and plasma	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/08 13:30
S6	7	plasma and S5	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/08 13:26
S7		plasma and etching and reactor and (heater adj (liner or jacket)) and controller and (substrate or wafer) near (holder or susceptor) and electrodes	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/08 13:48
S8	0	plasma and etching and (reactor or vessel or tank or container) and (heater adj (liner or jacket)) and controller and (substrate or wafer) near (holder or susceptor) and electrodes	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/08 13:49
S9	29354	plasma and etching and (reactor or vessel or tank or container) or (heater adj (liner or jacket)) and controller and (substrate or wafer) near (holder or susceptor) and electrodes	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON ,	2006/11/08 13:50
S10	1827	S2 and S9	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/08 13:51

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S11	534	S10 and electrostatic	US-PGPUB; USPAT;	OR .	ON	2006/11/08 13:52
		•	FPRS; EPO; JPO; DERWENT; IBM_TDB			
S12	22	S11 and fastener	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/13 13:24
S13	10454	156/345.35,345.37.ccls. 134/1/1, 104.1.ccls. 216/67.ccls. 438/730. ccls. 219/121.43,121.54,121.51, 411.ccls. 315/111.81.ccls. 118/723mp,724,725.ccls.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/13 13:40
S14	29400	plasma and etching and (reactor or vessel or tank or container) or (heater adj (liner or jacket)) and controller and (substrate or wafer) near (holder or susceptor) and electrodes	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/13 13:48
S15	1827	S13 and S14	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/13 13:40
S23	0	fluorine and passivation and (condensation near plasma) and (heated near continuously) and etching	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/13 13:52
S24	0	fluorine and (condensation near plasma) and (heated near continuously) and etching	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/13 13:52
S25	0	S15 and ((fluorine near etching) and (heat\$3 near continuous\$3))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/13 13:56

S26	688	S15 and fluorine	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/11/13 13:57
S27	20	S26 and (condensat\$4 near polymers)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON .	2006/11/13 13:58
S28	33359	(118/715.ccls. or 118/728.ccls. or 118/50.ccls. or 118/723e.ccls. or 118/723e.ccls. or 118/723e.ccls. or 118/723e.ccls. or 118/723e.ccls. or 156/345.26.ccls. or 156/345.29.ccls. or 156/345.33. ccls. or 156/345.34.ccls. or 156/345.35.ccls. or 156/345.36.ccls. or 156/345.43-345.47.ccls or 156/345.51.ccls.) or (137/262-264. ccls. or 137/454.2 or 137/560.ccls. or 137/561r.ccls. or 137/561a.ccls. or 137/571-576.ccls. or 137/590. ccls. or 137/594-596.ccls. or 137/599.01.ccls. or 137/602.ccls.) or (141/285-286.ccls. or 141/37.ccls. or 141/44-47.ccls. or 141/367.ccls.) or (261/127.ccls. or 261/131.ccls. or 261/146-147.ccls. or 261/150.ccls.) or (261/19-22.ccls. or 261/150.ccls.) or (261/62-63.ccls.) or (261/64.1.ccls. or 261/62-63.ccls.) or (261/64.1.ccls. or 261/62-63.ccls.) or (261/100-102. ccls. or 261/105.ccls. or 261/108-109.ccls. or 261/113.ccls. or 261/114.1.ccls.) or (118/723i. ccls. 118/723me. ccls. 118/723mr.ccls. 118/723ma. ccls. 156/345.35.ccls. 156/345.37. ccls.)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/16 10:54

S29	36071	(118/715.ccls. or 118/724.ccls. or 118/725.ccls. or 118/728.ccls. or 118/723e.ccls. or 118/723e.ccls. or 118/723e.ccls. or 118/723e.ccls. or 118/723e.ccls. or 156/345.26.ccls. or 156/345.29.ccls. or 156/345.33. ccls. or 156/345.34.ccls. or 156/345.35.ccls. or 156/345.36.ccls. or 156/345.35.ccls. or 156/345.36.ccls. or 156/345.43-345.47.ccls or 156/345.51.ccls.) or (137/262-264. ccls. or 137/454.2 or 137/560.ccls. or 137/561r.ccls. or 137/561a.ccls. or 137/571-576.ccls. or 137/590. ccls. or 137/594-596.ccls. or 137/599. 05-599.07.ccls. or 137/602.ccls.) or (141/285-286.ccls. or 141/37.ccls. or 141/37.ccls. or 141/44-47.ccls. or 141/367.ccls.) or (261/127.ccls. or 261/131.ccls. or 261/146-147.ccls. or 261/131.ccls. or 261/40.ccls. or 261/42.ccls. or 261/40.ccls. or 261/42.ccls. or 261/62-63.ccls.) or (261/64.1.ccls. or 261/65.ccls. or 261/100-102. ccls. or 261/108-109.ccls. or 261/100-102. ccls. or 261/114.1.ccls.) or (118/723i. ccls. 118/723me. ccls. 118/723mr.ccls. 118/723ma.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/12 13:45
S30	· 16	ccls. 156/345.35.ccls. 156/345.37. ccls.) S29 and (plasma same ((substrate or wafer) with electrostatic)) and (liner with (chamber or vessel) with heat\$2) and (liner with (aluminum or titanium)) and ((support or pedestal) near\$3 bias\$2)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/12 14:05
S31	39	puech-michel.in.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 08:58
S32	1	S31 and (plasma same liner)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 09:01

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C:\Documents and Settings\jng1\My Documents\EAST\Workspaces\10516457 - Etching Reactor with Heater Liner and Method by Puech

S33	26	S31 and plasma	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 09:02
S34	25	S33 not S32	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 13:45
S35	36076	(118/715.ccls. or 118/724.ccls. or 118/725.ccls. or 118/728.ccls. or 118/723e.ccls. or 118/50.ccls. or 118/723e.ccls. or 118/723er.ccls. or 118/723er.ccls. or 156/345.26.ccls. or 156/345.29.ccls. or 156/345.33. ccls. or 156/345.34.ccls. or 156/345.35.ccls. or 156/345.35.ccls. or 156/345.36.ccls. or 156/345.43-345.47.ccls or 156/345.51.ccls.) or (137/262-264. ccls. or 137/454.2 or 137/560.ccls. or 137/561r.ccls. or 137/561a.ccls. or 137/571-576.ccls. or 137/590. ccls. or 137/599.01.ccls. or 137/599. 05-599.07.ccls. or 137/602.ccls.) or (141/285-286.ccls. or 141/37.ccls. or 141/44-47.ccls. or 141/367.ccls.) or (261/127.ccls. or 261/131.ccls. or 261/146-147.ccls. or 261/131.ccls. or 261/146-22.ccls. or 261/123.1.ccls. or 261/62-63.ccls.) or (261/64.1.ccls. or 261/65.ccls. or 261/75-76.ccls. or 261/108-109.ccls. or 261/100-102. ccls. or 261/108-109.ccls. or 261/113.ccls. or 261/114.1.ccls.) or (118/723i. ccls. 118/723mr.ccls. 118/723me. ccls. 118/723mr.ccls. 156/345.37. ccls.)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 13:41
S36	15	S35 and (plasma same (detach\$4 with (liner or shield or protect\$3)))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 09:33

S37	16	S35 and (plasma same ((substrate or wafer) with electrostatic)) and (liner with (chamber or vessel) with heat\$2) and (liner with (aluminum or titanium)) and ((support or pedestal) near\$3 bias\$2)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 09:33
S38	15	S36 not S37	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 09:34
S39	36076	(118/715.ccls. or 118/724.ccls. or 118/725.ccls. or 118/728.ccls. or 118/50.ccls. or 118/723e.ccls. or 118/50.ccls. or 118/723e.ccls. or 118/723er.ccls. or 156/345.26.ccls. or 156/345.29.ccls. or 156/345.33. ccls. or 156/345.34.ccls. or 156/345.35.ccls. or 156/345.36.ccls. or 156/345.35.ccls. or 156/345.36.ccls. or 156/345.43-345.47.ccls or 156/345.51.ccls.) or (137/262-264. ccls. or 137/454.2 or 137/560.ccls. or 137/561r.ccls. or 137/561a.ccls. or 137/571-576.ccls. or 137/590. ccls. or 137/599.01.ccls. or 137/599. 05-599.07.ccls. or 137/602.ccls.) or (141/285-286.ccls. or 141/37.ccls. or 141/301-302.ccls. or 141/367.ccls.) or (261/127.ccls. or 261/131.ccls. or 261/146-147.ccls. or 261/131.ccls. or 261/40.ccls. or 261/123.1.ccls. or 261/40.ccls. or 261/42.ccls. or 261/62-63.ccls.) or (261/64.1.ccls. or 261/62-63.ccls.) or (261/64.1.ccls. or 261/62-63.ccls.) or (261/100-102. ccls. or 261/105.ccls. or 261/113.ccls. or 261/108-109.ccls. or 261/113.ccls. or 261/114.1.ccls.) or (118/723i. ccls. 118/723mr.ccls. 118/723ma. ccls. 118/723mr.ccls. 118/723ma. ccls. 156/345.35.ccls. 156/345.37. ccls.)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 11:37
S40	195	S39 and ((plasma with chamber) and (chamber same ((liner or shield) with heat\$2)))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 14:06

S41	39	puech-michel.in.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 13:50
S42	26	S41 and plasma	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 13:50
S43	195	S40 not S42	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 13:50
S44		S39 and ((plasma with chamber) and (chamber adj ((liner or shield) with heat\$2)))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 14:07
S45	195	S39 and ((plasma with chamber) and (chamber adj ((liner or shield))))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/13 14:08
S46	46	("4340462" "4399546" "4579618" "4701427" "4710428" "4786359" "4863657" "4948458" "4981551" "4999228" "5006220" "5085727" "5182059" "5198718" "5200232" "5241245" "5262029" "5277751" "5292399" "5304279" "5324411" "5367139" "5399237" "5401350" "5409563" "5441568" "544217" "5460684" "5463525" "5494523" "5538230" "5556501" "5569356" "5584936" "5611955" "5725675" "5728253" "5788799" "5792304" "5863376" "5891350" "5904778" "6048798" "6129808").PN. OR ("6464843").URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 15:03

S47	54	("3951587" "4340462" "4401689" "4518349" "4598665" "4761134" "4948458" "4999228" "5006220" "5022979" "5051134" "5074456" "5182059" "5200232" "5252892" "5262029" "5292399" "5391275" "5431964" "5454901" "5460684" "5463524" "5494524" "5538230" "5569356" "5578129" "5595627" "5665168" "5712198" "5744401" "5766684" "5820723" "5837662" "5838529" "5863376" "5888907" "5892236"	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/13 16:49
		"5904778" "5937316" "6054373" "6068729" "6159297").PN. OR ("6506254").URPN.				
S48	2	"7001491".pn.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR .	ON .	2007/03/14 16:32
S49	2	"6527911".pn.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/14 16:37
S50	2	"20030188685".pn.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 09:46
S51	18	(US-20060029542-\$ or US-20050224178-\$ or US-20020168467-\$ or US-20030188685-\$).did. or (US-6302966-\$ or US-6394026-\$ or US-6454898-\$ or US-6506254-\$ or US-6554979-\$ or US-6716302-\$ or US-5391275-\$ or US-5595627-\$ or US-6227140-\$ or US-6129808-\$ or US-5788799-\$ or US-6562186-\$ or US-6726801-\$).did. or (JP-2001127049-\$).did.	US-PGPUB; USPAT; JPO	OR	ON	2007/03/15 11:08
S52	51	("5338399").PN. OR ("5595627"). URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 11:31

CE3	36000	(118/715 ccls or 118/724 ccls or	IIS-DCDI IR.	OR	ON	2007/03/20 10:34
S53	36080	(118/715.ccls. or 118/724.ccls. or 118/725.ccls. or 118/723e.ccls. or 118/723e.ccls. or 118/723e.ccls. or 118/723er.ccls. or 118/723er.ccls. or 156/345.26.ccls. or 156/345.29.ccls. or 156/345.33. ccls. or 156/345.34.ccls. or 156/345.35.ccls. or 156/345.35.ccls. or 156/345.36.ccls. or 156/345.43-345.47.ccls or 156/345.51.ccls.) or (137/262-264. ccls. or 137/454.2 or 137/561a.ccls. or 137/571-576.ccls. or 137/590. ccls. or 137/599.01.ccls. or 137/599. 05-599.07.ccls. or 137/602.ccls.) or (141/285-286.ccls. or 141/37.ccls. or 141/44-47.ccls. or 141/367.ccls.) or (261/127.ccls. or 261/131.ccls. or 261/146-147.ccls. or 261/131.ccls. or 261/140.ccls. or 261/42.ccls. or 261/62-63.ccls.) or (261/127.ccls. or 261/64.1.ccls. or 261/65.ccls. or 261/75-76.ccls. or 261/94-96.ccls. or 261/100-102. ccls. or 261/114.1.ccls. or 261/113.ccls. or 261/114.1.ccls. or 261/113.ccls. or 261/114.1.ccls. or 261/113.ccls. or 261/114.1.ccls. or 261/113.ccls. or 261/114.1.ccls. or 118/723me. ccls. 118/723mr.ccls. 118/723ma. ccls. 118/723mr.ccls. 156/345.37. ccls.)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/20 10:34
S54	0	S53 and ((chamber adj (liner or shield)) same (heat\$2 near infrared))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 11:39
S55	265	S53 and (chamber adj (liner or shield))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:40
S56		S55 and (heat\$3 near infrared)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 12:40

S57	22	S53 and ((gas near flow) same (control\$3 with (solenoid adj valve)))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 12:04
S58	6	S57 and plasma	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 12:04
S59		S55 and (heat\$3 near thermocoaxial)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 12:41
S60	6	S55 and (heat\$3 near ribbon)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON .	2007/03/15 12:41
S61	15	S55 and ((liner or shield) near (attach\$4 or fasten\$2))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:01
S62	1	S61 and (hook or hanger)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 13:59
S63	15	S55 and ((liner or shield) near (attach\$4 or fasten\$2 or hang\$2))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:16
S64	0	S63 not S61	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:07

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S65	18	S55 and ((liner or shield) near	US-PGPUB;	OR	ON	2007/03/15 14:17
		(attach\$4 or fasten\$2 or hang\$2 or suspend\$2 or hung))	USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB			
S66	3	S65 not S61	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:17
S67	2	"20060096532".pn.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:23
S68	0	("2006/0096532").URPN.	USPAT	OR	ON	2007/03/15 14:23
S69	0	S63 and (teflon adj screw)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:40
S70		S63 and (liner near screw)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:40
S71	0	S65 and (liner near screw)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:41
S72	1	S65 and (shield near screw)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR .	ON	2007/03/15 14:41
S73	42	("5223111" "5368648" "5419029" "5518593" "5538603" "5565071").PN. OR ("5690795"). URPN.	US-PGPUB; USPAT; USOCR	OR	ON	2007/03/15 14:53

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S74	5	S73 and ((shield or liner) near (attach\$2 or fasten\$3 or suspend\$2 or hang or hung))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 14:55
S75	0	S61 and teflon	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:01
S76	8	S61 and screws	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:02
S77	22	S57 not S54	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:02
S78	8	S76 not S74	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:31
S79		"6342277".pn.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:32
S80·	18	S53 and ((chamber with plasma) same ((liner or shield) near (attach\$2 or fasten\$2 or hang or hung or suspend\$2)))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:35
S81	15	S80 not S65	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:36

S82	15	S81 not S76	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:36
S83	15	S81 not (S73 or S61)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 15:37
S84	276	(keyhole adj shape) with slot	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/16 10:54
S85	173	S84 and (fasten\$2 or attach\$2 or suspend\$2 or hang or hung)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 22:09
S86	28	S84 and ((fasten\$2 or attach\$2 or suspend\$2 or hang or hung) with keyhole)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/15 22:09

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S87	33367	(118/715.ccls. or 118/728.ccls. or	US-PGPUB;	OR	ON	2007/03/16 10:54
İ		118/50.ccls. or 118/723e.ccls. or 118/723er.ccls. or 156/345.26.ccls.	USPAT; FPRS;			
		or 156/345.29.ccls. or 156/345.33.	EPO; JPO;			
		ccls. or 156/345.34.ccls. or	DERWENT;			
		156/345.35.ccls. or 156/345.36.ccls.	IBM_TDB			
		or 156/345.43-345.47.ccls or	1011_100			
		156/345.51.ccls.) or (137/262-264.				
		ccls. or 137/454.2 or 137/560.ccls.				
	•	or 137/561r.ccls. or 137/561a.ccls.				
		or 137/571-576.ccls. or 137/590.				
		ccls. or 137/594-596.ccls. or				
	•	137/599.01.ccls. or 137/599.				
		05-599.07.ccls. or 137/602.ccls.) or				
		(141/285-286.ccls. or 141/37.ccls.				
		or 141/44-47.ccls. or 141/54.ccls. or				
		141/301-302.ccls. or 141/367.ccls.)				
		or (261/127.ccls. or 261/131.ccls. or				
		261/146-147.ccls. or 261/150.ccls.)				
		or (261/19-22.ccls. or 261/23.1.ccls.				
		or 261/40.ccls. or 261/42.ccls. or				
		261/62-63.ccls.) or (261/64.1.ccls.				·
		or 261/65.ccls. or 261/75-76.ccls. or				
		261/94-96.ccls. or 261/100-102.				
		ccls. or 261/105.ccls. or				
		261/108-109.ccls. or 261/113.ccls.				
		or 261/114.1.ccls.) or (118/723i.				
		ccls. 118/723ir.ccls. 118/723me.				
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		ccls. 156/345.35.ccls. 156/345.37.				
		ccls.)		-		
coo	•	•	LIC DCDLID.	OD	ON	2007/02/16 10:55
S88	0	S87 and ((keyhole adj shape) with	US-PGPUB;	OR	ON	2007/03/16 10:55
		slot)	USPAT;			
			FPRS;			
			EPO; JPO;			
			DERWENT;			
			IBM_TDB			
S89	1	S87 and ((keyhole adj shape))	US-PGPUB;	OR	ON	2007/03/16 10:55
			USPAT;			
		,	FPRS;			
			EPO; JPO;			
			DERWENT;			
			IBM_TDB			
S90	25	S87 and ((keyhole))	US-PGPUB;	OR	ON	2007/03/16 10:56
		co. and ((neyholo))	USPAT;			
			FPRS;			
			EPO; JPO;			•
			DERWENT;			
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			1	T		
S91	7	S90 and plasma	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/16 11:07
S92	18	S90 not S91	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/16 11:07
S93	52	S87 and (plasma and (chamber same (infrared adj lamp)))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/16 12:46
S94	38	S93 and etch\$3	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/16 12:50
S95	0	S93 and (infrared with benefit)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/16 12:51
S96	0	S93 and (infrared with good)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/16 12:51
S97	4	"3880396".pn.	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/19 09:29

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28	(US-20060029542-\$ or	US-PGPUB; USPAT;	OR	ON	2007/03/20 09:57
	US-20050224178-\$ or US-20020168467-\$ or	,			
	US-20060096532-\$ or	3. 0			
	US-20030188685-\$).did. or				
	(US-5788799-\$ or US-6227140-\$ or				
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	US-5391275-\$ or US-5935395-\$ or				
	US-4439463-\$ or US-5314541-\$ or				
•	did. or (JP-2001127049-\$).did.				
16	S98 and ((aluminum or titanium) with (shield or liner))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT;	OR	ON	2007/03/20 10:00
		IBW_LDB			
4	S99 and ((electrostatic and bias)	US-PGPUB;	OR	ON	2007/03/20 10:02
	and (temperature same control\$3))	USPAT; FPRS; EPO; JPO; DERWENT;			
		US-20030188685-\$).did. or (US-5788799-\$ or US-6227140-\$ or US-6129808-\$ or US-6394026-\$ or US-6716302-\$ or US-65454898-\$ or US-6302966-\$ or US-6562186-\$ or US-6554979-\$ or US-6506254-\$ or US-5968379-\$ or US-5885356-\$ or US-6726801-\$ or US-6120660-\$ or US-5690795-\$ or US-5935395-\$ or US-4439463-\$ or US-5314541-\$ or US-6926803-\$ or US-3880396-\$). did. or (JP-2001127049-\$).did. S98 and ((aluminum or titanium) with (shield or liner))	US-20060096532-\$ or US-20030188685-\$).did. or (US-5788799-\$ or US-6227140-\$ or US-6129808-\$ or US-6394026-\$ or US-6716302-\$ or US-6562186-\$ or US-6302966-\$ or US-6506254-\$ or US-6554979-\$ or US-5885356-\$ or US-6726801-\$ or US-5955627-\$ or US-5990795-\$ or US-5935395-\$ or US-4439463-\$ or US-5314541-\$ or US-6926803-\$ or US-3880396-\$). did. or (JP-2001127049-\$).did. 16 S98 and ((aluminum or titanium) with (shield or liner)) 4 S99 and ((electrostatic and bias) and (temperature same control\$3)) 4 US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB 4 S99 and ((electrostatic and bias) and (temperature same control\$3))	US-20060096532-\$ or US-20030188685-\$).did. or (US-5788799-\$ or US-6227140-\$ or US-6129808-\$ or US-6394026-\$ or US-6716302-\$ or US-6552186-\$ or US-6554979-\$ or US-6506254-\$ or US-5788799-\$ or US-5885356-\$ or US-6726801-\$ or US-595627-\$ or US-599795-\$ or US-5995627-\$ or US-4439463-\$ or US-5314541-\$ or US-6926803-\$ or US-3880396-\$). did. or (JP-2001127049-\$).did. 16 S98 and ((aluminum or titanium) with (shield or liner)) 4 S99 and ((electrostatic and bias) and (temperature same control\$3)) 4 S99 and ((electrostatic and bias) and (temperature same control\$3)) 6 US-PGPUB; US-PGPUB	US-20060096532-\$ or US-20030188685-\$).did. or (US-5788799-\$ or US-6227140-\$ or US-6129808-\$ or US-6394026-\$ or US-6716302-\$ or US-6454898-\$ or US-6302966-\$ or US-6562186-\$ or US-6554979-\$ or US-5885356-\$ or US-5968379-\$ or US-5885356-\$ or US-5960795-\$ or US-5935395-\$ or US-5391275-\$ or US-5935395-\$ or US-6926803-\$ or US-3880396-\$). did. or (JP-2001127049-\$).did. 16 S98 and ((aluminum or titanium) with (shield or liner)) 4 S99 and ((electrostatic and bias) and (temperature same control\$3)) 4 US-PGPUB; US-PGPU

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S10 1	36088	(118/715.ccls. or 118/724.ccls. or 118/725.ccls. or 118/728.ccls. or 118/723e.ccls. or 118/50.ccls. or 118/723e.ccls. or 118/723er.ccls. or 118/723er.ccls. or 156/345.26.ccls. or 156/345.29.ccls. or 156/345.33. ccls. or 156/345.34.ccls. or 156/345.35.ccls. or 156/345.35.ccls. or 156/345.36.ccls. or 156/345.43-345.47.ccls or 156/345.51.ccls.) or (137/262-264. ccls. or 137/454.2 or 137/560.ccls. or 137/561r.ccls. or 137/561a.ccls. or 137/571-576.ccls. or 137/590. ccls. or 137/594-596.ccls. or 137/599.01.ccls. or 137/602.ccls.) or (141/285-286.ccls. or 141/37.ccls. or 141/44-47.ccls. or 141/367.ccls. or 141/44-47.ccls. or 141/367.ccls.) or (261/127.ccls. or 261/131.ccls. or 261/146-147.ccls. or 261/131.ccls. or 261/40.ccls. or 261/42.ccls. or 261/40.ccls. or 261/64.1.ccls. or 261/62-63.ccls.) or (261/64.1.ccls. or 261/65.ccls. or 261/75-76.ccls. or 261/94-96.ccls. or 261/100-102. ccls. or 261/114.1.ccls. or 261/113.ccls. or 261/108-109.ccls. or 261/113.ccls. or 261/108-109.ccls. or 261/113.ccls. or 261/114.1.ccls.) or (118/723i. ccls. 118/723me. ccls. 118/723mr.ccls. 118/723ma. ccls. 156/345.35.ccls. 156/345.37. ccls.)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/20 10:37
S10 2	96	S101 and ((plasma same (gas with alternat\$3)) same control\$3)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/20 10:38
S10 3	2	S102 and ((etching with passivation) with gas)	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/20 10:42
S10 4	94	S102 not S103	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/20 15:27

S10 5	11	S101 and ((carbon adj monoxide) with (deposition or passivation))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/20 15:28
S10 6	299	S101 and (etch\$3 with ((carbon adj monoxide) or argon))	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/20 17:09
S10 7	6	S106 not argon	US-PGPUB; USPAT; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/03/20 17:09

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